Welcome to NACK's Webinar

# Introduction to Nanofabrication: Top Down to Bottom Up

NACK is an NSF-funded ATE Resource Center supporting faculty in Nanotechnology Education

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NACK is the NSF ATE National Center for Nanotechnology Applications and Career Knowledge

The NACK National Center is located at Penn State University



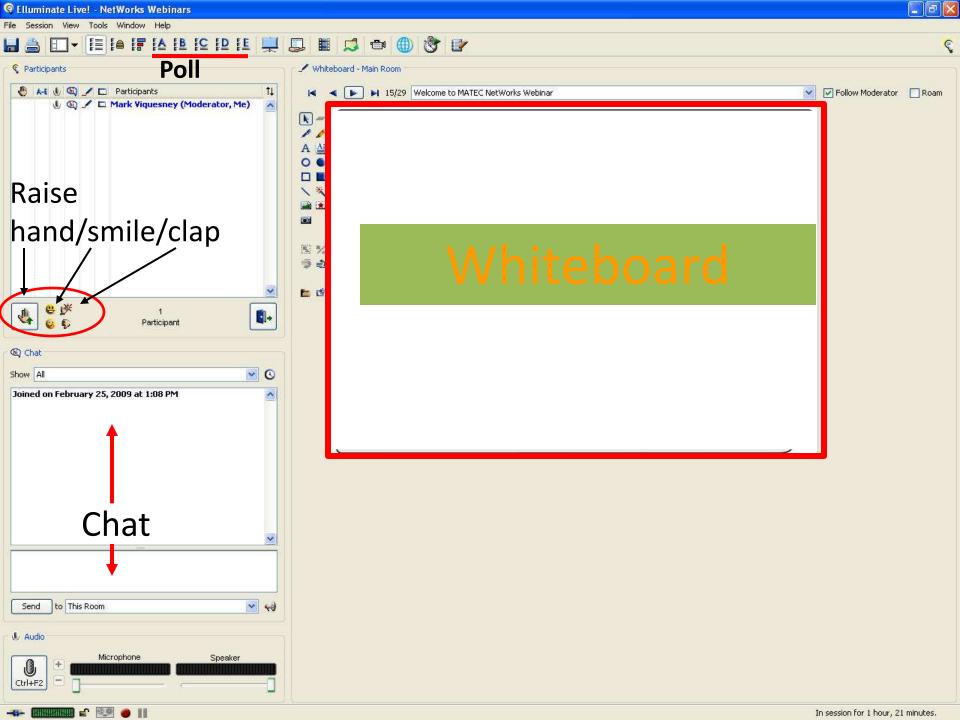
National Science Foundation

Funded, in part, by a grant from the National Science Foundation. DUE-08020498











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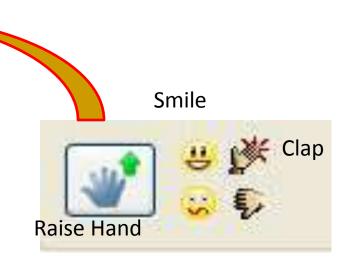
#### Participant's Box

Allows you to non-verbally respond to the presenter's comments.





# Participant's Box



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#### NACK's Webinar Presenter



Presented by Dave Johnson Research Assistant The Pennsylvania State University Center for Nanotechnology Education and Utilization djohnson@engr.psu.edu 814-865-0319







- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)









- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)
  - Deposition (or film growth)









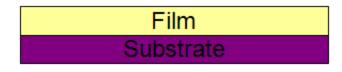
- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)
  - Deposition (or film growth)
  - Etching ( or removal of material)



- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)
  - Deposition (or film growth)
  - Etching ( or removal of material)
- Basic bottom-up approaches in nanofabrication



Starts with thin films of materials supported by a substrate



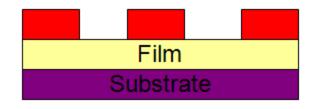








 Nanoscale features are defined through a patterning process



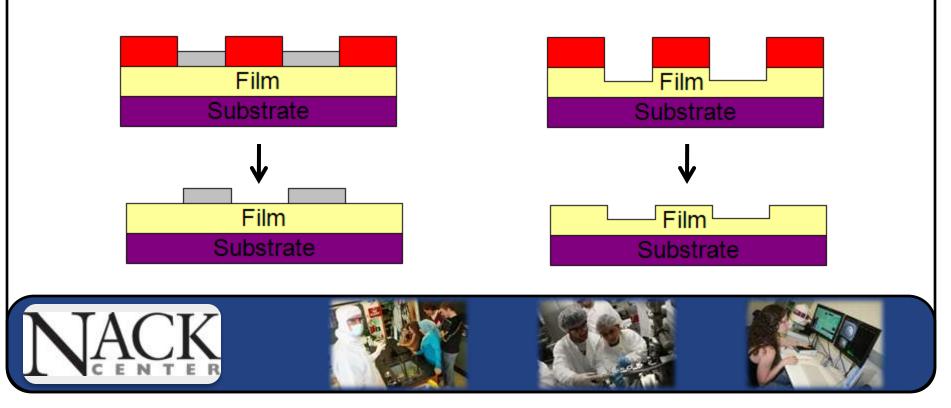








 Nanoscale features from the pattern are then transferred to the substrate through additive or subtractive processes



• These steps are performed many times to create complex nanostructures









- Patterning Process: Photolithography
  - A light sensitive material called photoresist is applied to the substrate

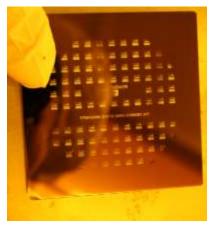






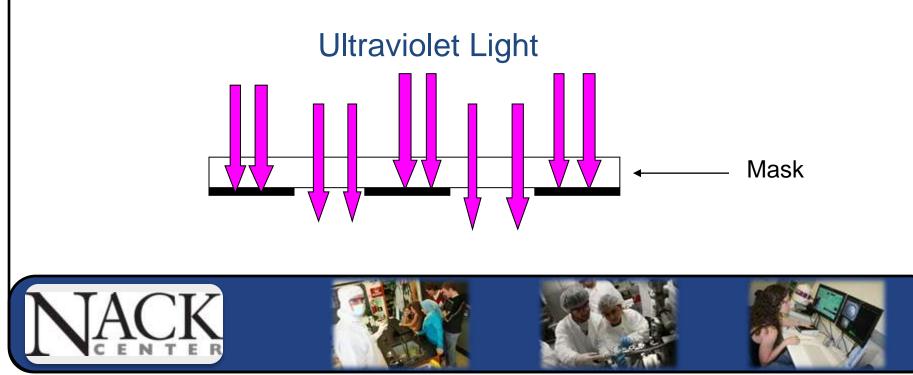


- Patterning Process: Photolithography
  - A light sensitive material called photoresist is applied to the substrate
  - A photomask is aligned to the substrate





- A photomask is used to determine which portions of the resist film are exposed to the UV light.
  - Made of glass or quartz with a chrome pattern
  - Even the mask needs to be made with lithography!



- Patterning Process: Photolithography
  - A light sensitive material called photoresist is applied to the substrate
  - A photomask is aligned to the substrate
  - The substrate is exposed to UV light



- Patterning Process: Photolithography
  - A light sensitive material called photoresist is applied to the substrate
  - A photomask is aligned to the substrate
  - The substrate is exposed to UV light
  - The exposed photoresist is developed

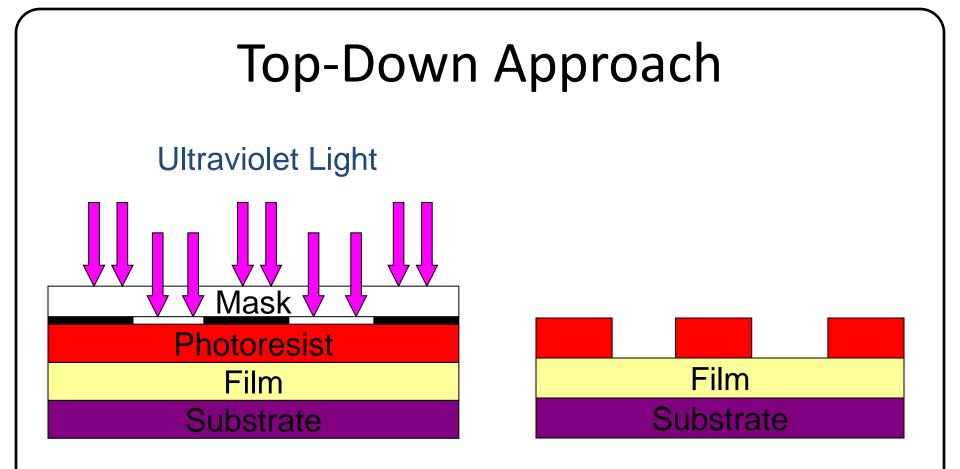


- Patterning Process: Photolithography
  - A light sensitive material called photoresist is applied to the substrate
  - A photomask is aligned to the substrate
  - The substrate is exposed to UV light
  - The exposed photoresist is developed
  - The pattern is checked for quality



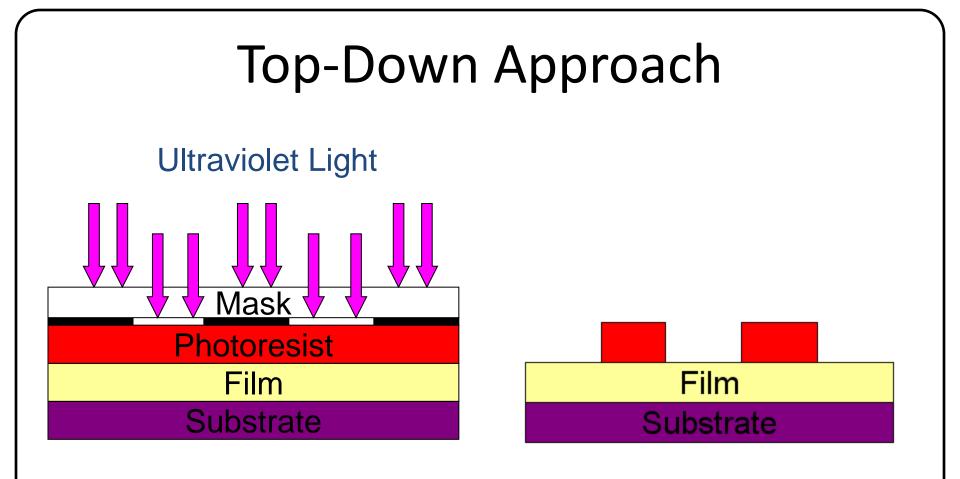
- There are two general types of UV sensitive photoresists
  - Positive resists
  - -Negative resists





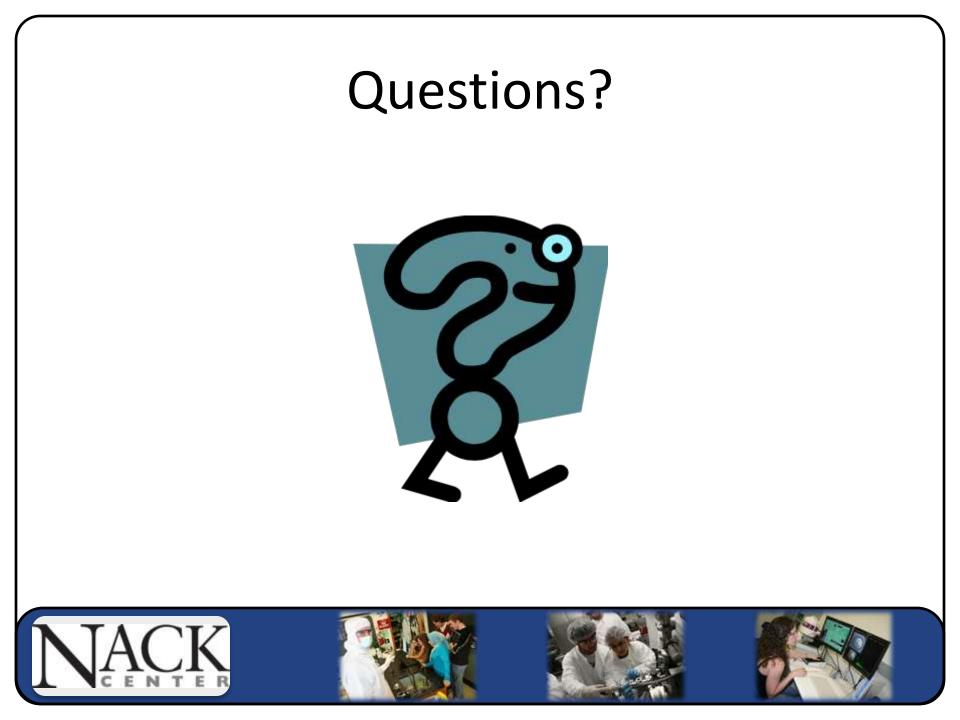
• This is an example of positive tone photoresist - "what shows, goes!"





• This is an example of negative tone photoresist - "what shows, stays!"





- Additive Processes: Deposition, Growth & Implantation
  - Deposition
    - Typically requires energy to perform the process



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  - Growth typically means there is consumption of the substrate to create a new material
    - Typically requires high heat and chemical reactions



- Additive Processes: Deposition, Growth & Implantation
  - Deposition
    - Typically requires energy to perform the process
  - Growth typically means there is consumption of the substrate to create a new material
    - Typically requires high heat and chemical reactions
  - Implantation
    - Used to modify the optical, mechanical, electrical, or etch characteristics of a material
    - Typically requires a heating step to anneal the sample



- Physical Vapor Deposition
  - Evaporation











#### Evaporation

- Create a vacuum



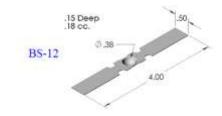






#### Evaporation

- Create a vacuum
- Melt metal pellets
  - Alloys and insulators are difficult to evaporate







#### Evaporation

Increase temperature so that molten metal evaporates

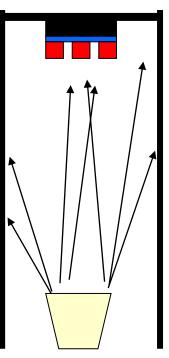






#### Evaporation

- Metal vapor condenses onto your sample











- Physical Vapor Deposition
  - Sputtering

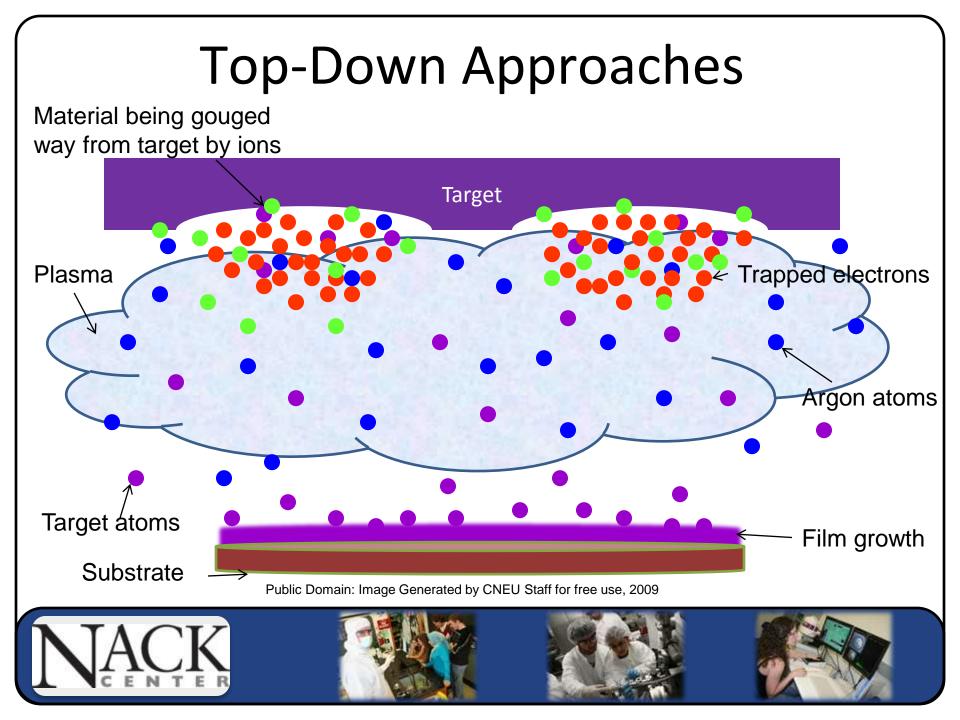


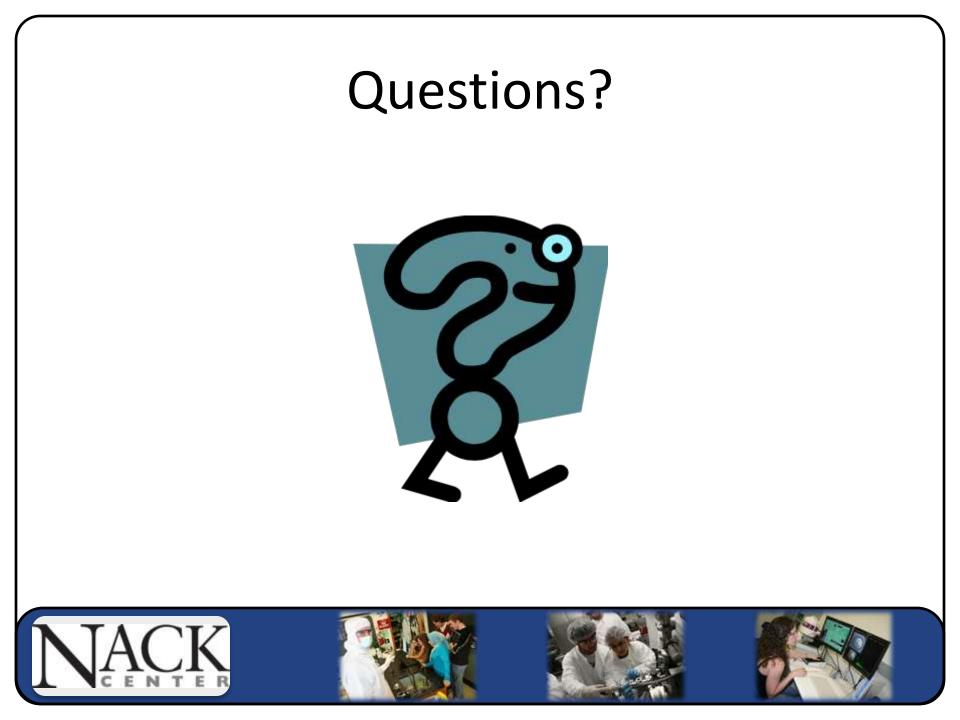












- Chemical Vapor Deposition:
  - Low Pressure Chemical Vapor Deposition







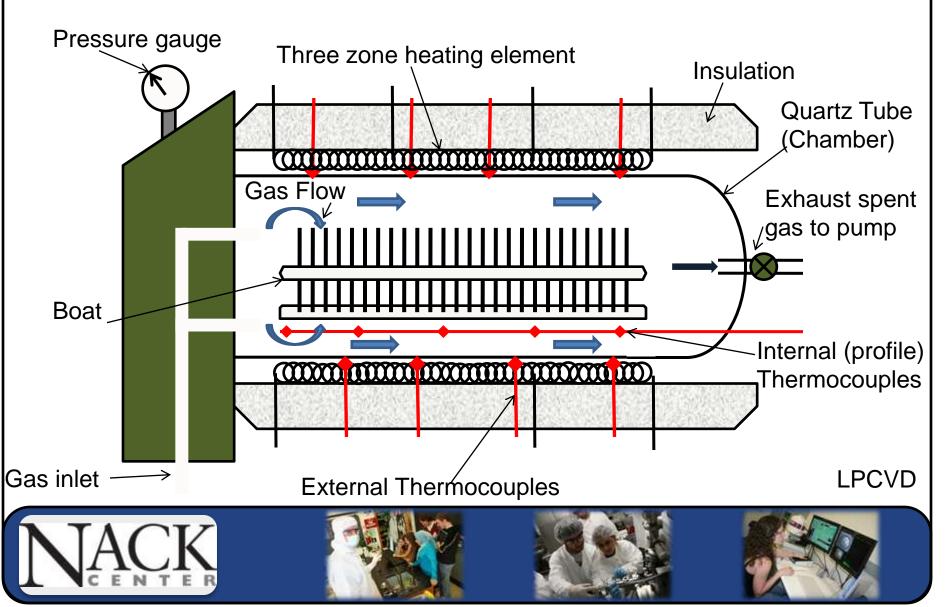


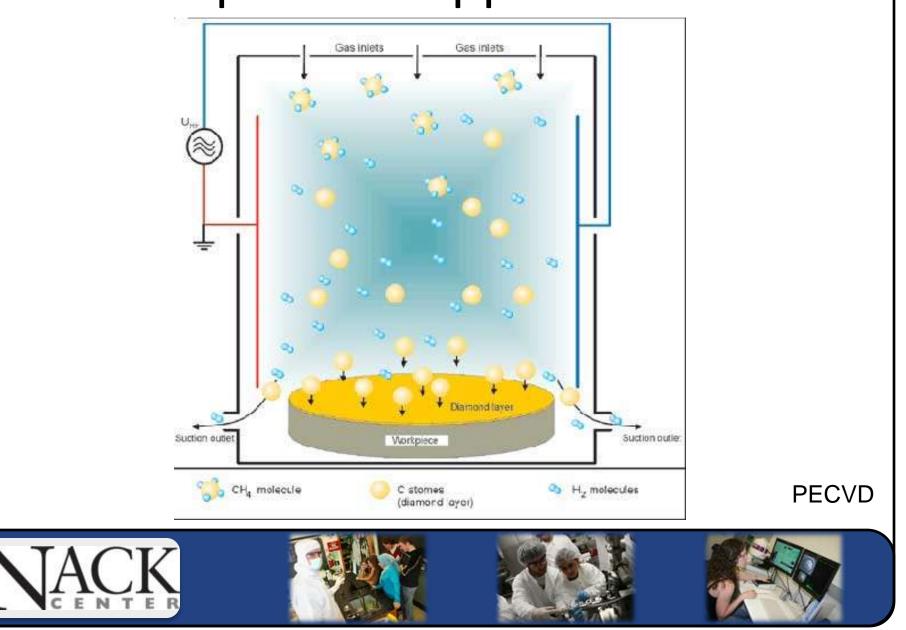
- Chemical Vapor Deposition:
  - Low Pressure Chemical Vapor Deposition
  - Plasma Enhanced Chemical Vapor Deposition

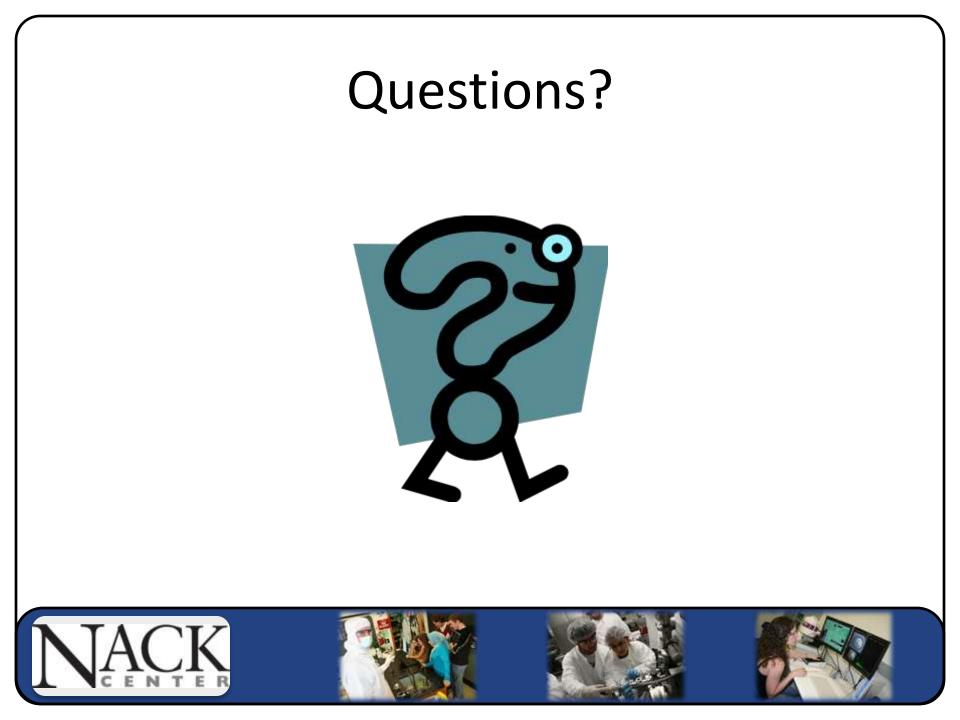












- Subtractive Objects: Wet Etching
  - Uses liquid chemistry to chemical react with substrate materials











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  - For patterned amorphous materials wet etchants produce isotropic etch profiles





- Subtractive Objects: Wet Etching
  - Uses liquid chemistry to chemical react with substrate materials
  - For patterned amorphous materials wet etchants produce isotropic etch profiles
  - Isotropic features are just as wide as they are





deep

- Subtractive Objects: Reactive Ion Etching
  - Use plasma to ionize gas









- Subtractive Objects: Reactive Ion Etching
  - Use plasma to ionize gas
  - Processing gas is selected for chemical etching of substrate materials



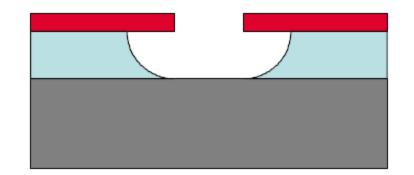
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  - Use plasma to ionize gas
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  - A negative bias is place on substrate to allows for physical etching from positively charged gas species.



- Subtractive Objects: Reactive Ion Etching
  - Use plasma to ionize gas
  - Processing gas is selected for chemical etching of substrate materials
  - A negative bias is place on substrate to allows for physical etching from positively charged gas species.
  - The pressure of they system determines the etch profile of the sample

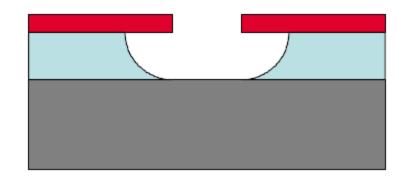


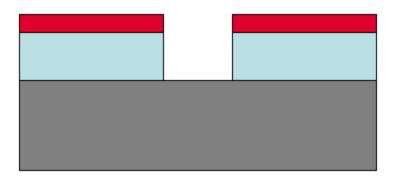
- High pressure etching (100s mT)
  - Creates a small Mean Free Path
  - Promotes a chemical etch
  - Creates isotropic etch profiles



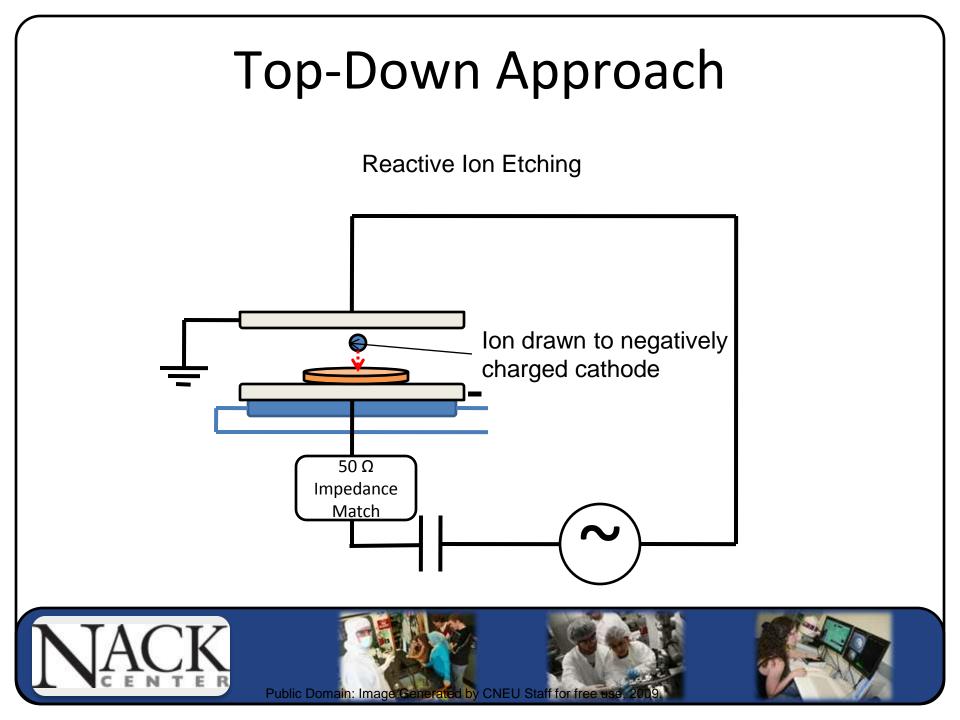


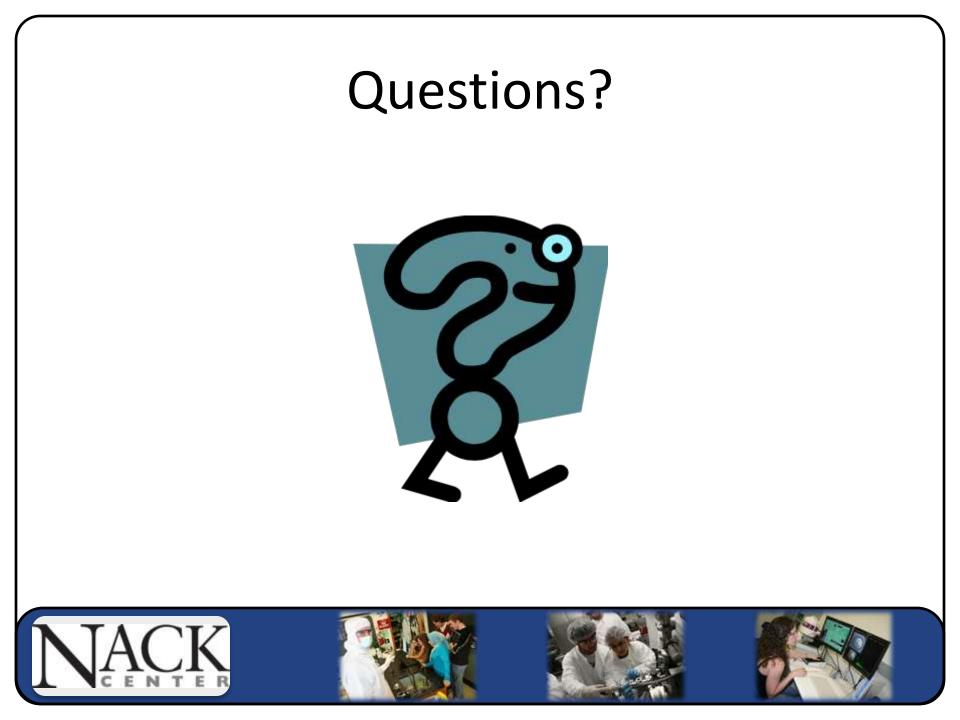
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  - Creates anisotropic etch profiles

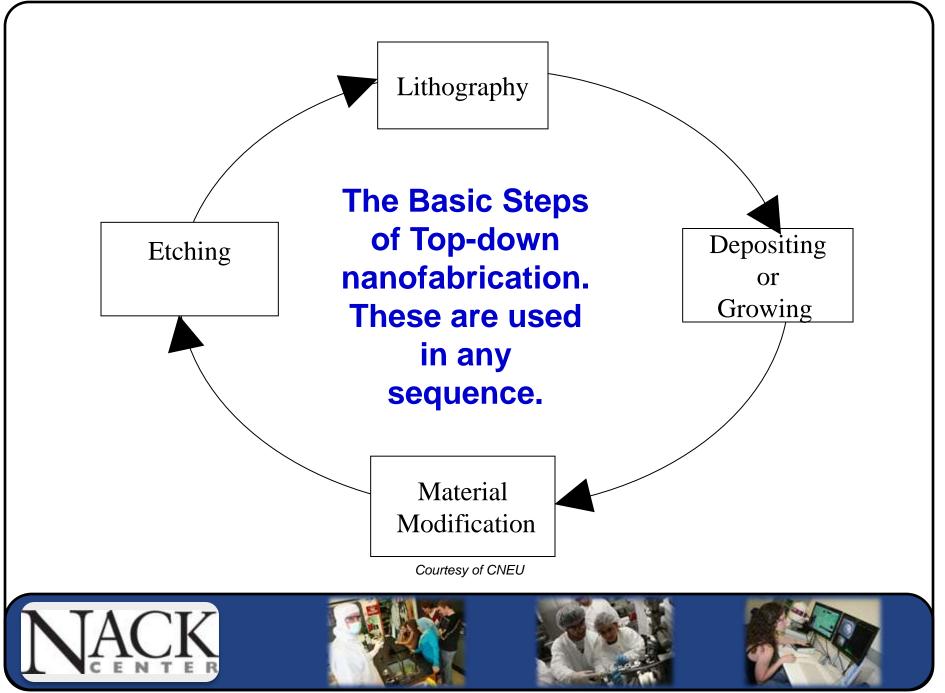












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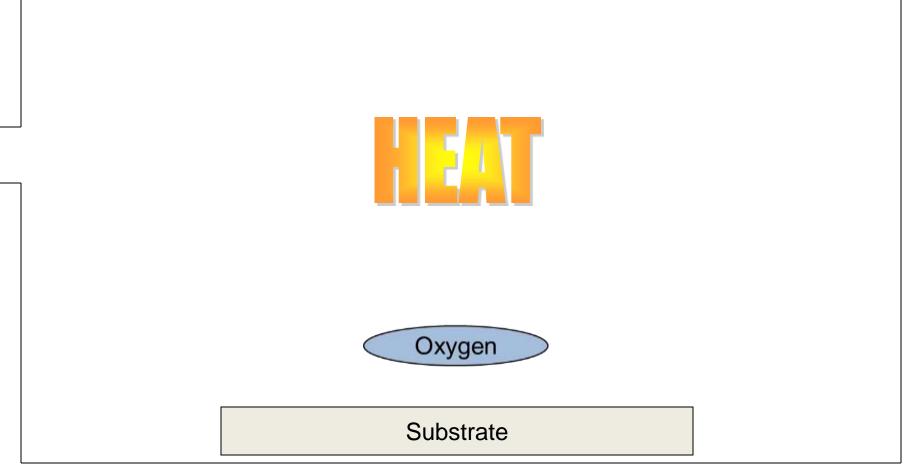
Film Grown by Chemical Reaction of Ambient species with the Substrate

#### Substrate

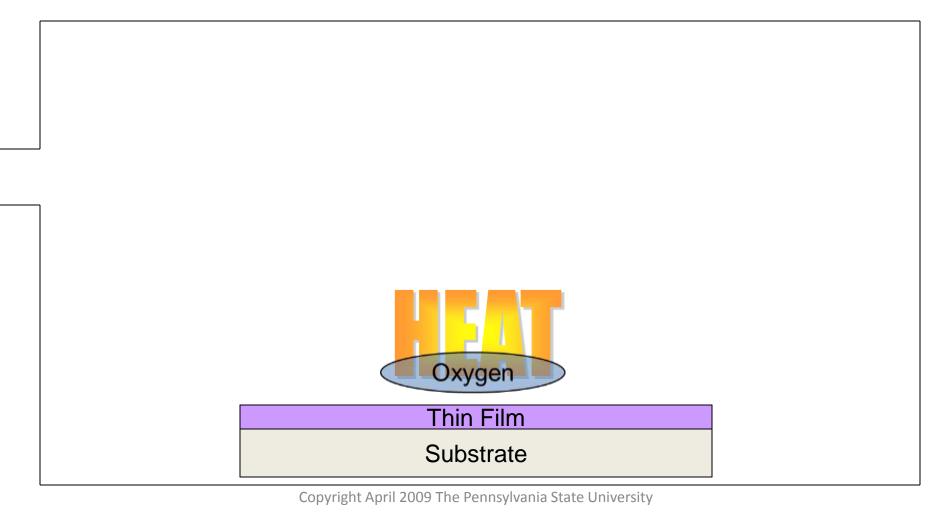
Film Grown by Chemical Reaction of Ambient species with the Substrate

$\langle$	Oxygen		
		Substrate	

Film Grown by Chemical Reaction of Ambient species with the Substrate



Film Grown by Chemical Reaction of Ambient species with the Substrate



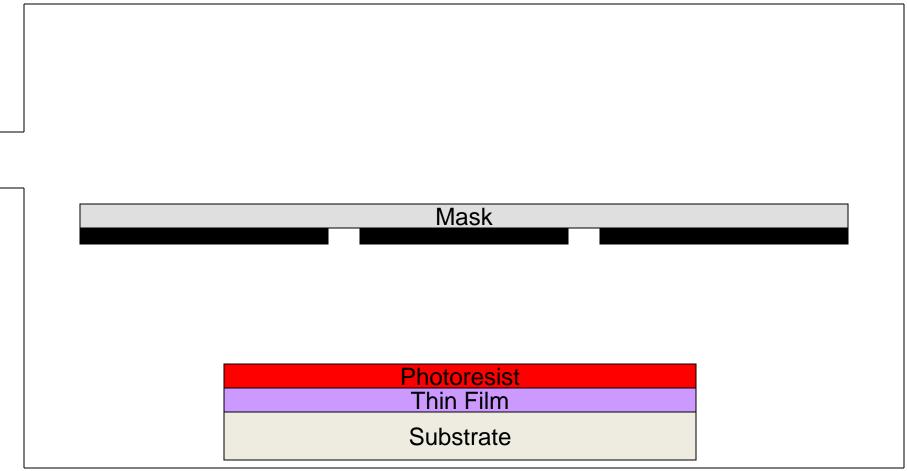
Spin on Photoresist

]		
	Thin Film	
	Substrate	

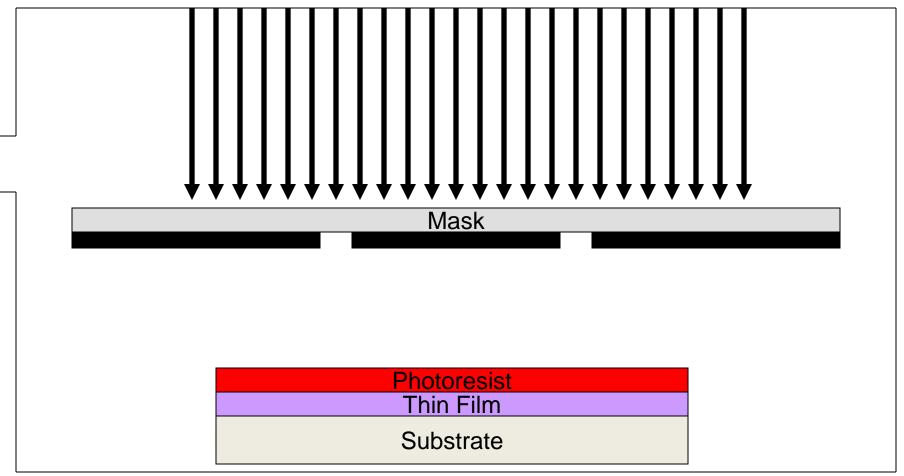
Spin on Photoresist

		Photoresist		
		Thin Film		
		Substrate		
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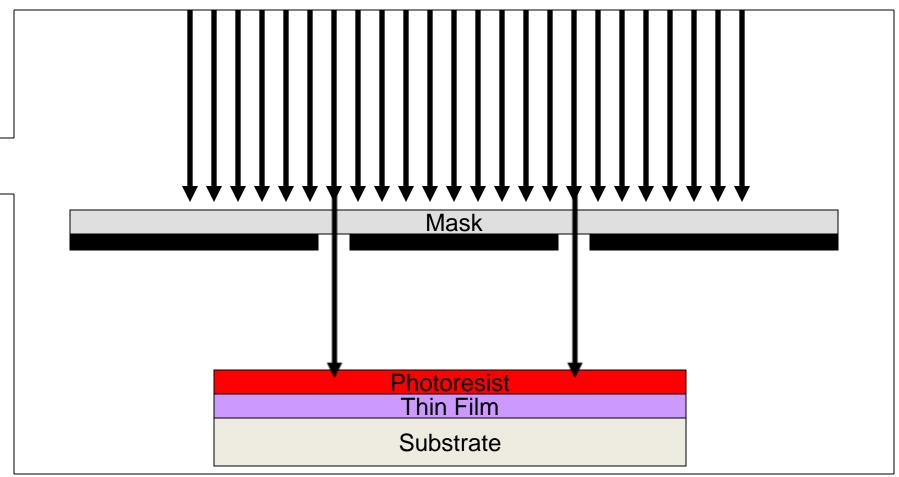
Align Photomask



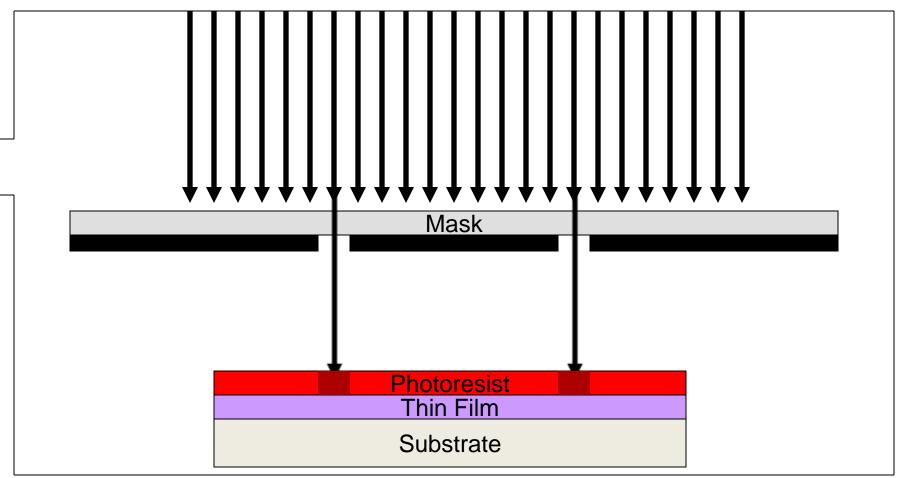
Expose with Light



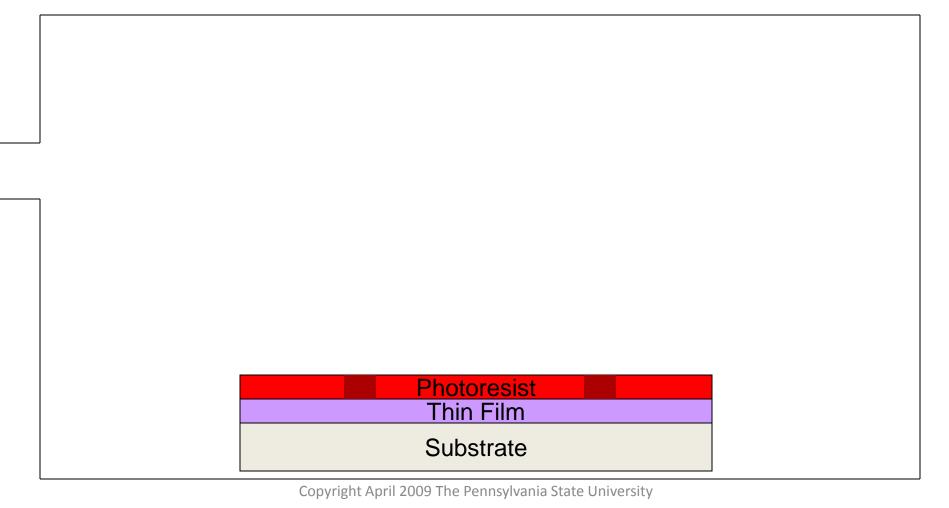
Expose with Light



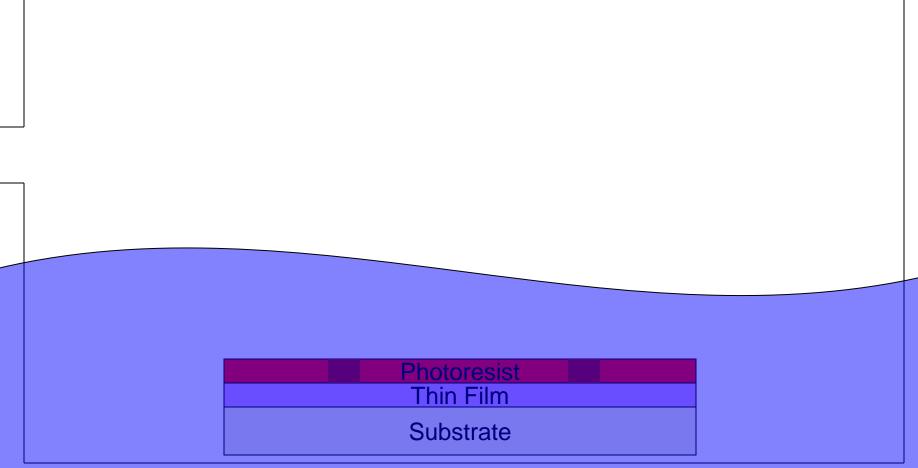
Chemical Bonds are Altered in Exposed Areas



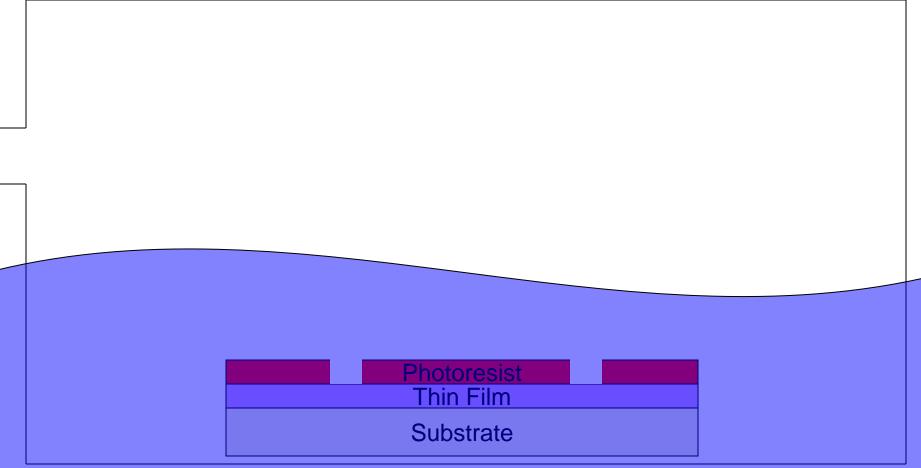
**Dissolve Exposed Photoresist in Liquid Developer** 



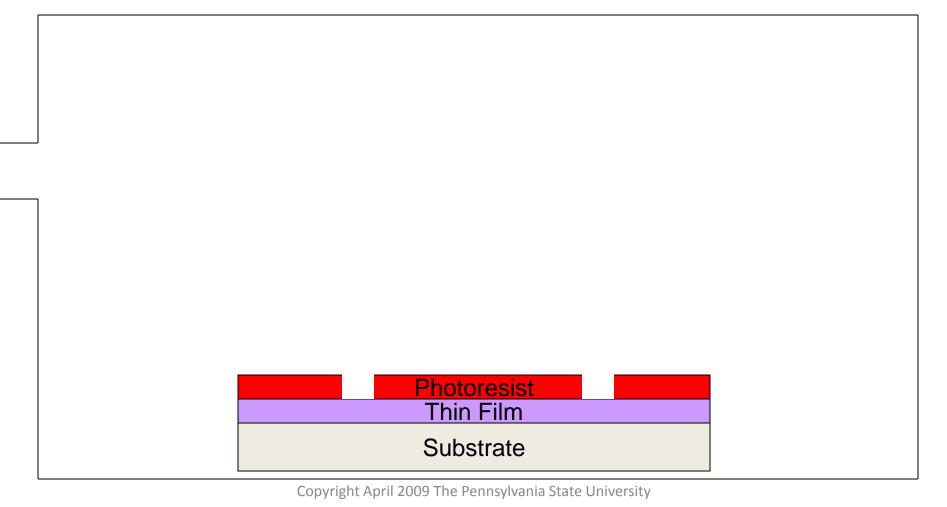
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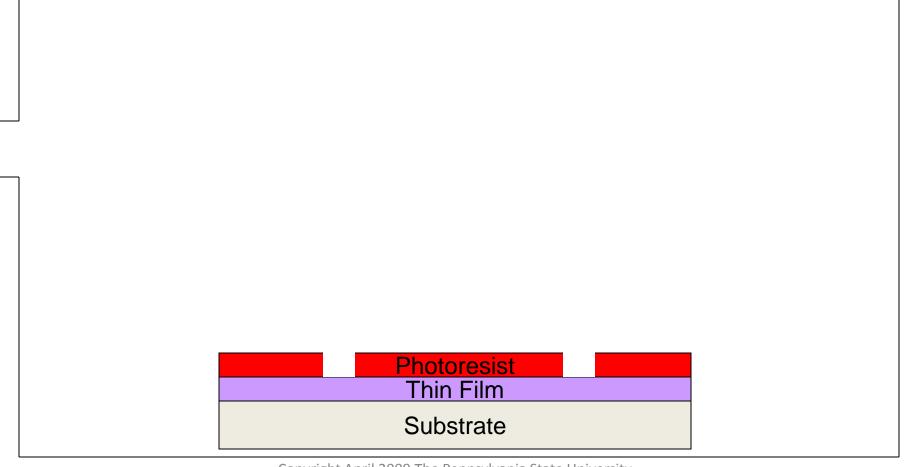


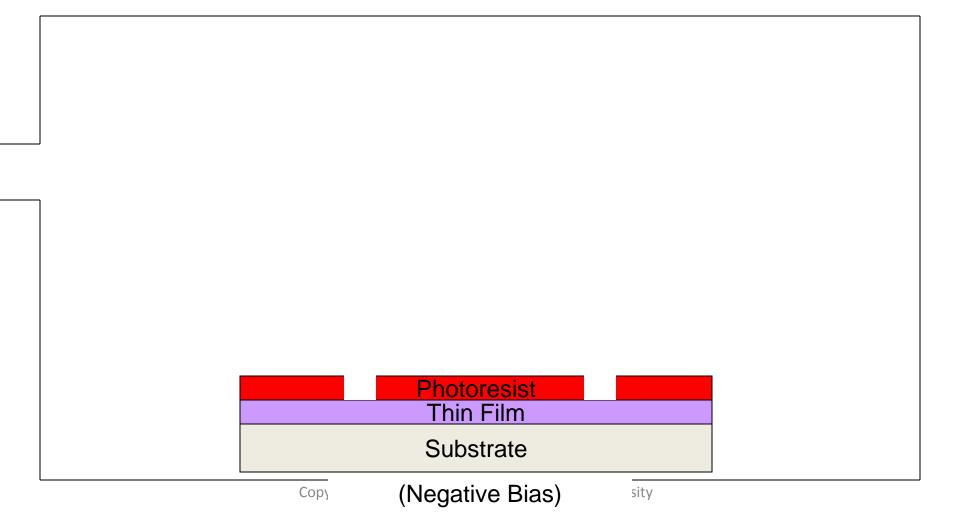
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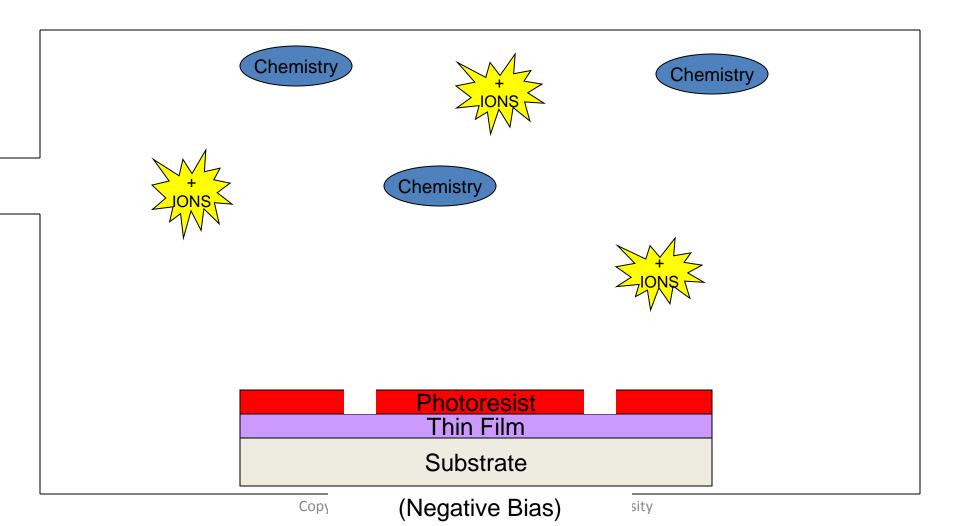


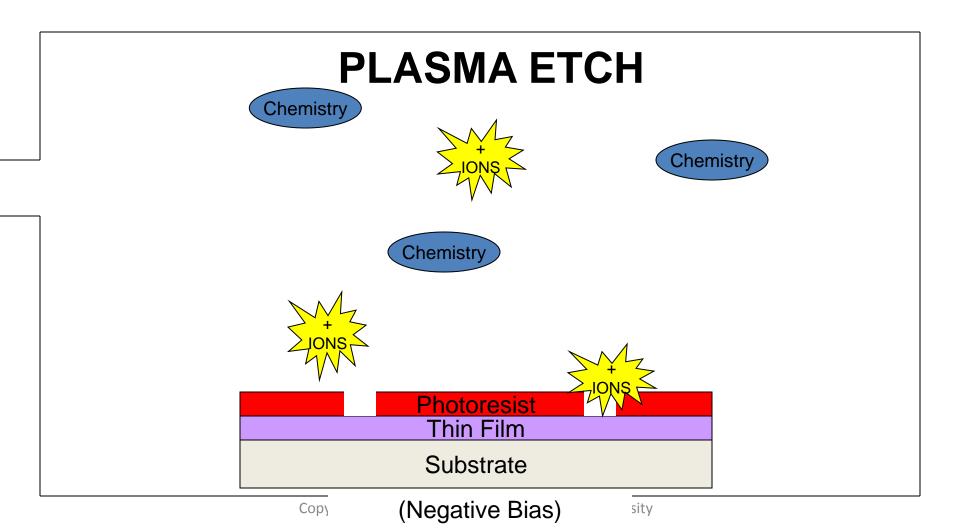
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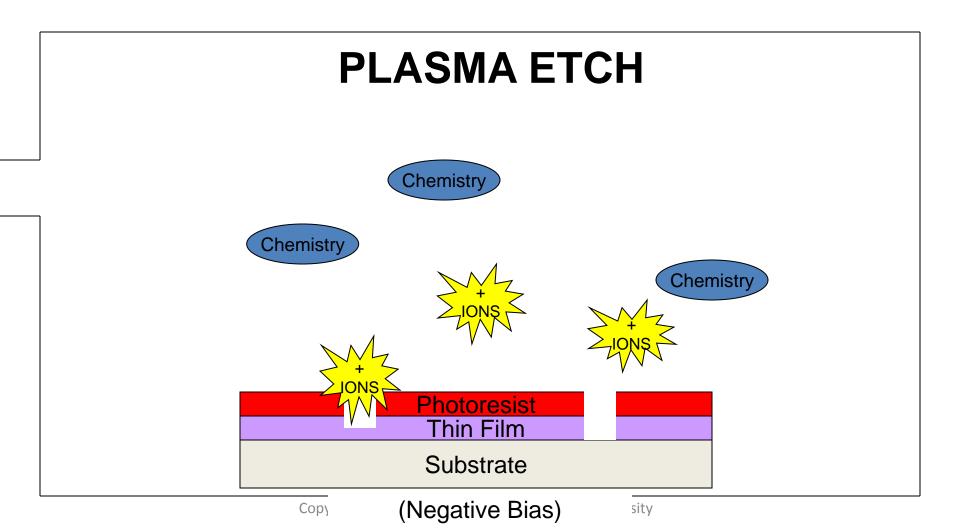


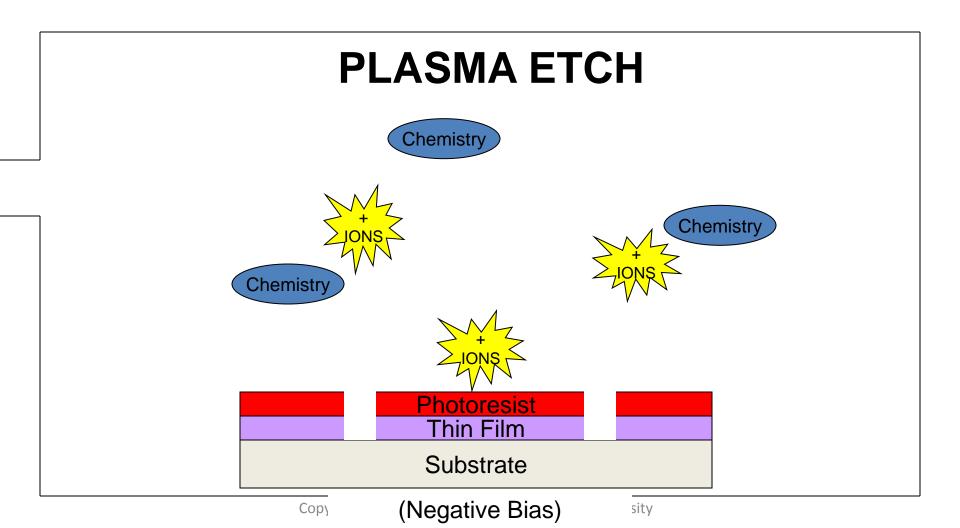


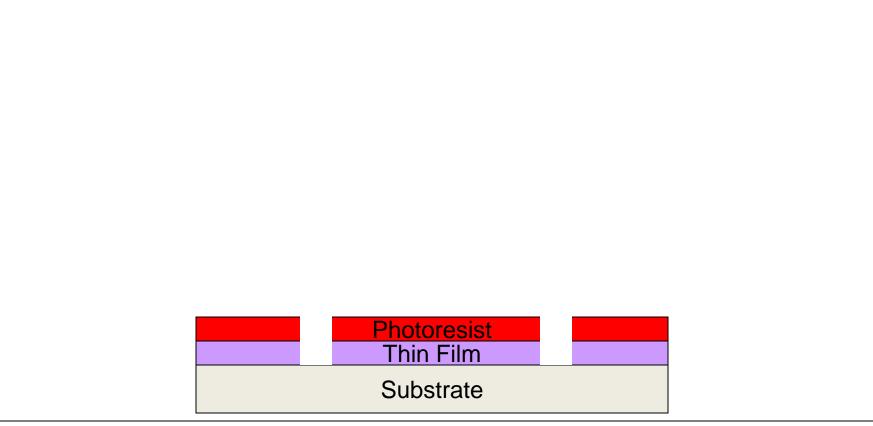


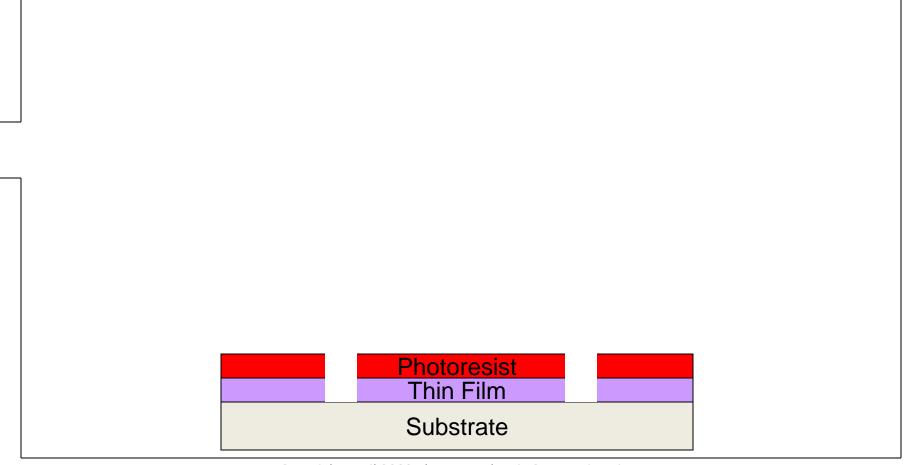


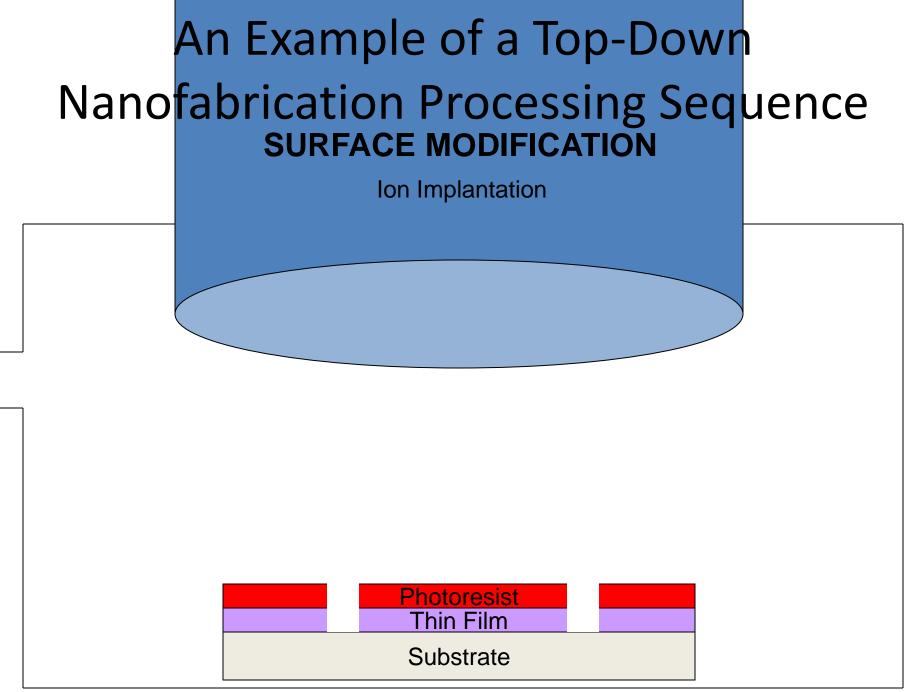


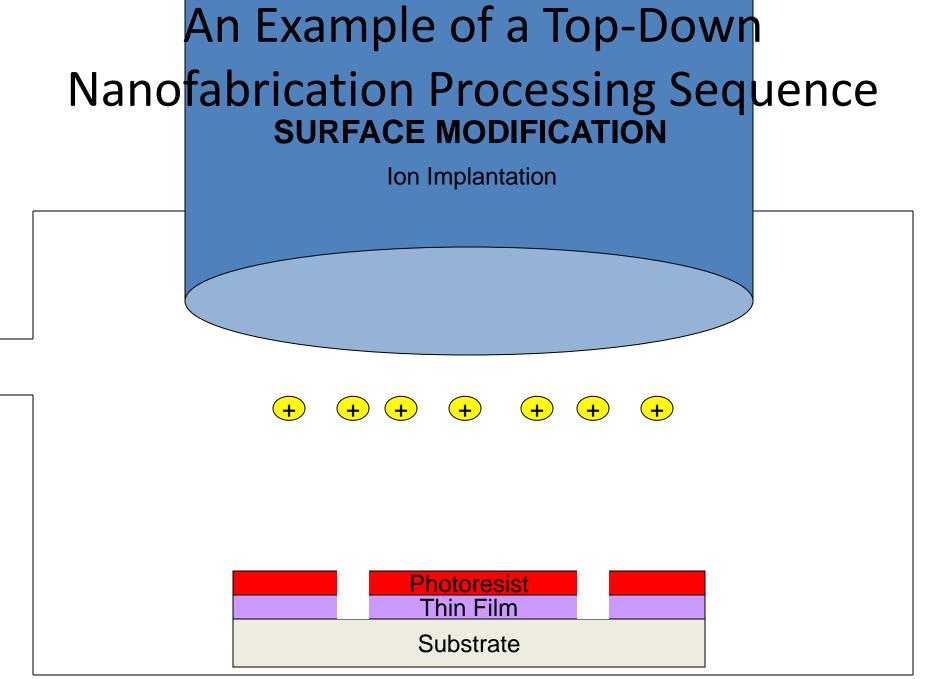


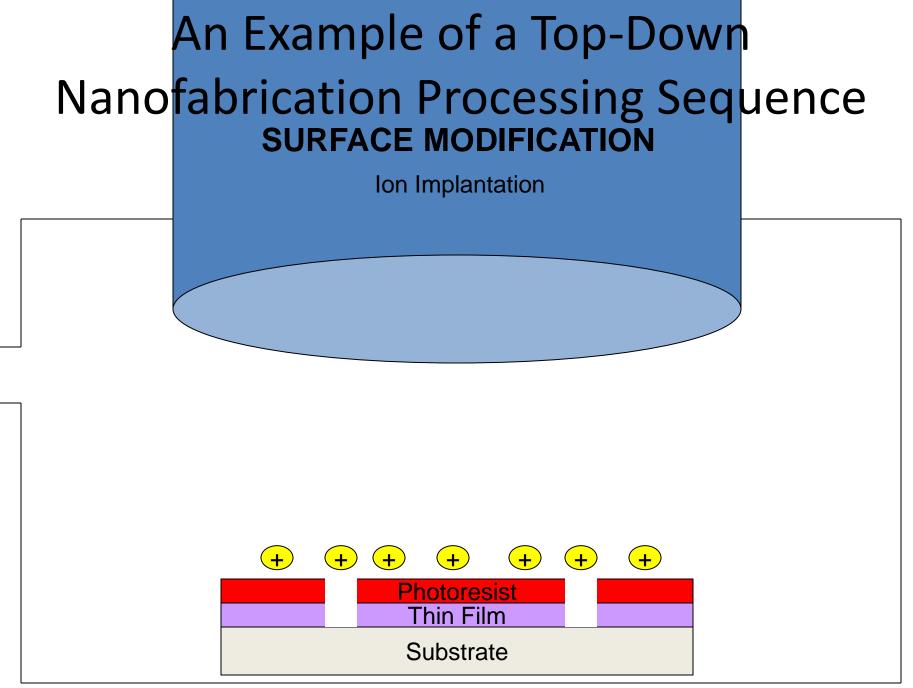


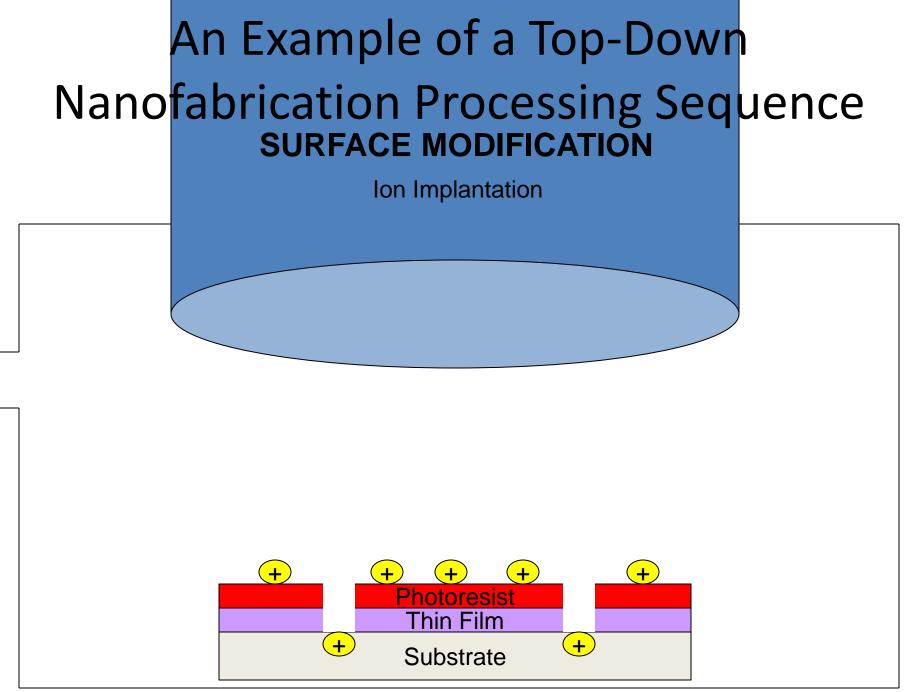


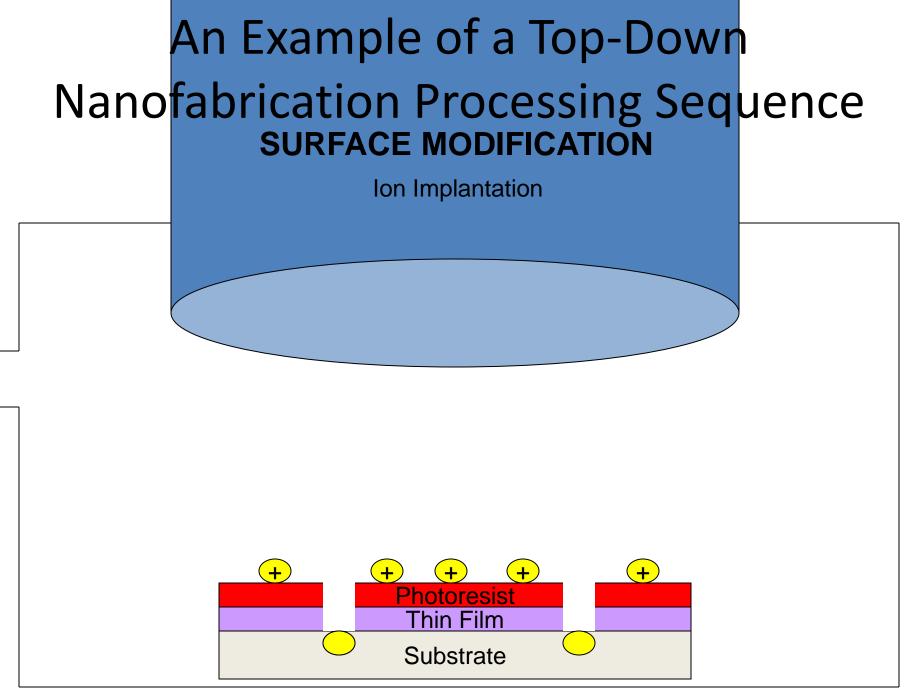


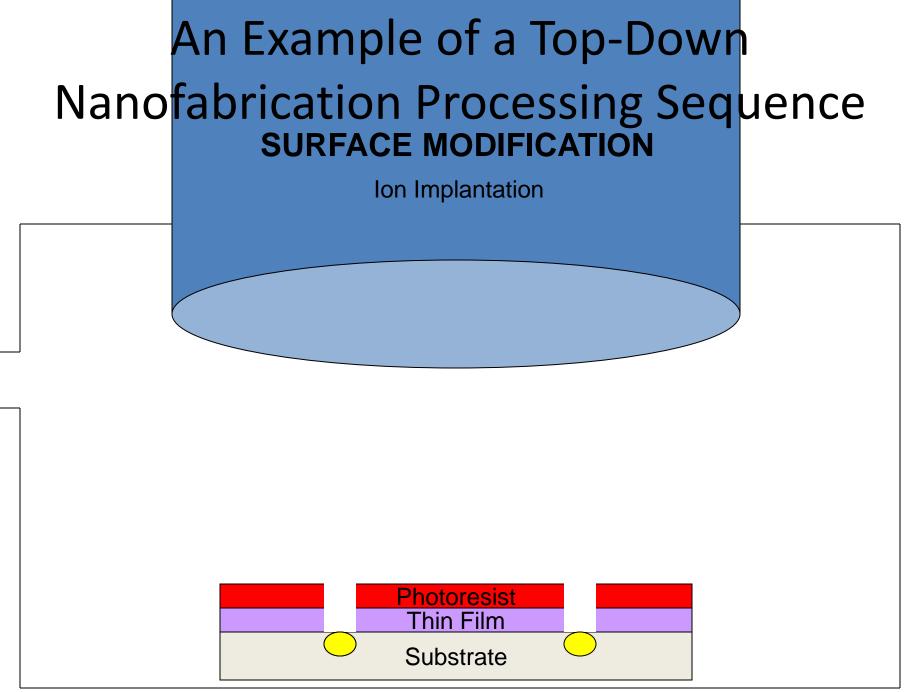




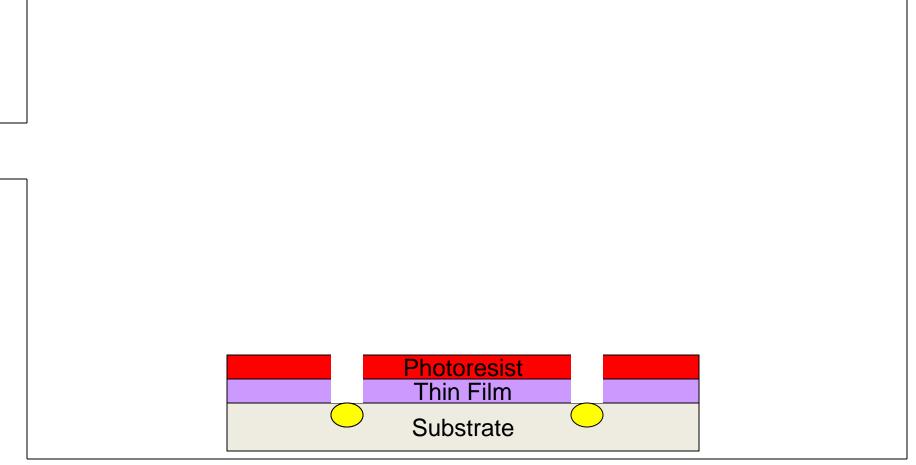




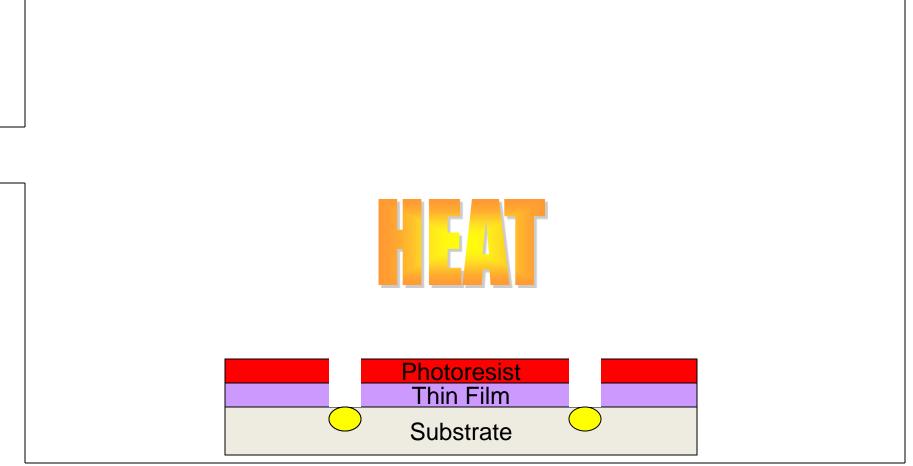




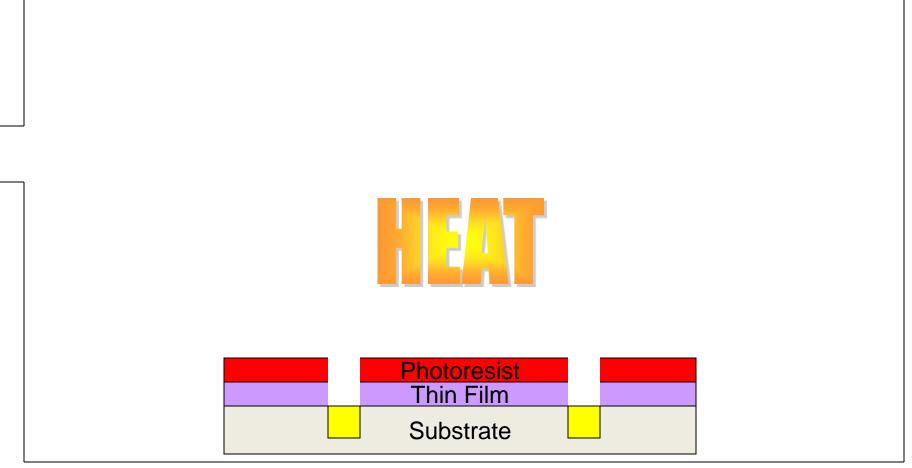
**Thermal Anneal** 



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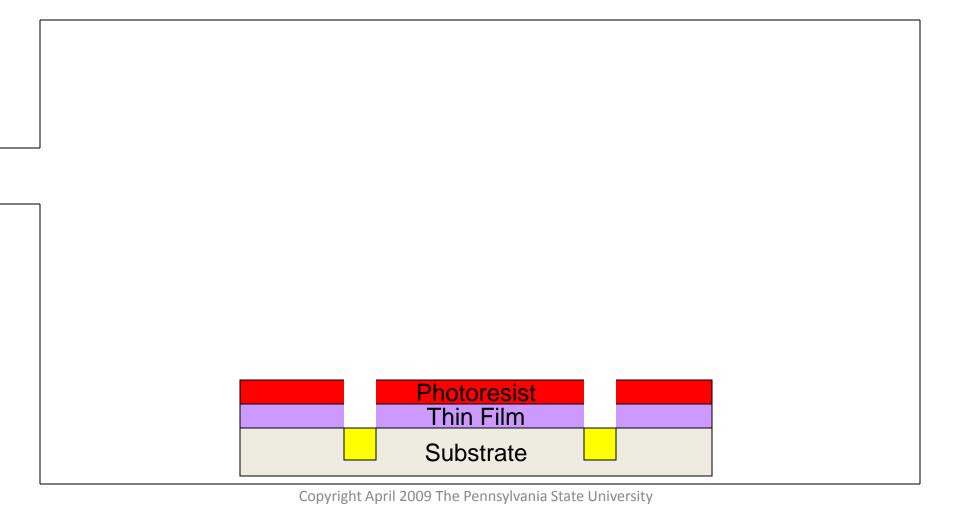
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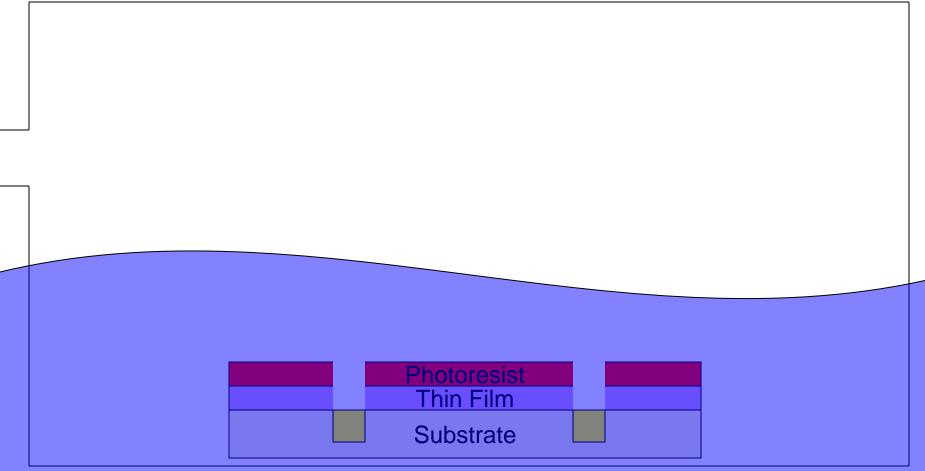
**Thermal Anneal** 

Photoresist   Thin Film
Substrate
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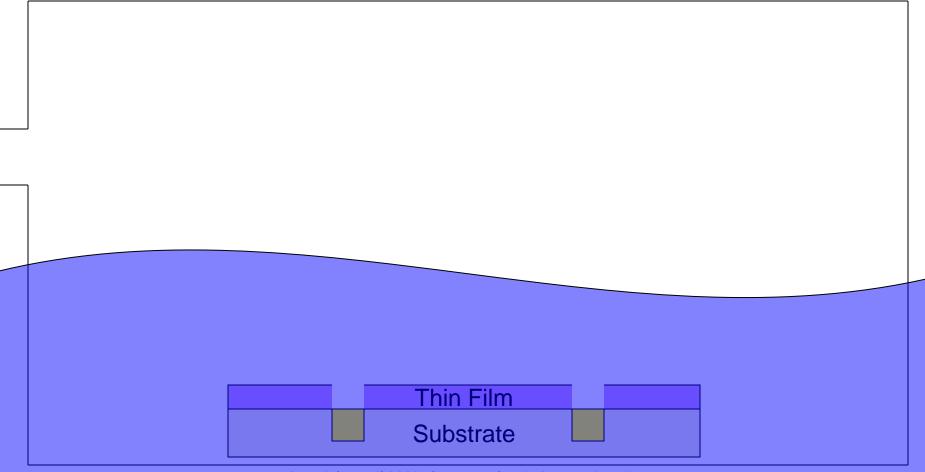
Remove the Photoresist (Etch/Ion Implantation) Barrier



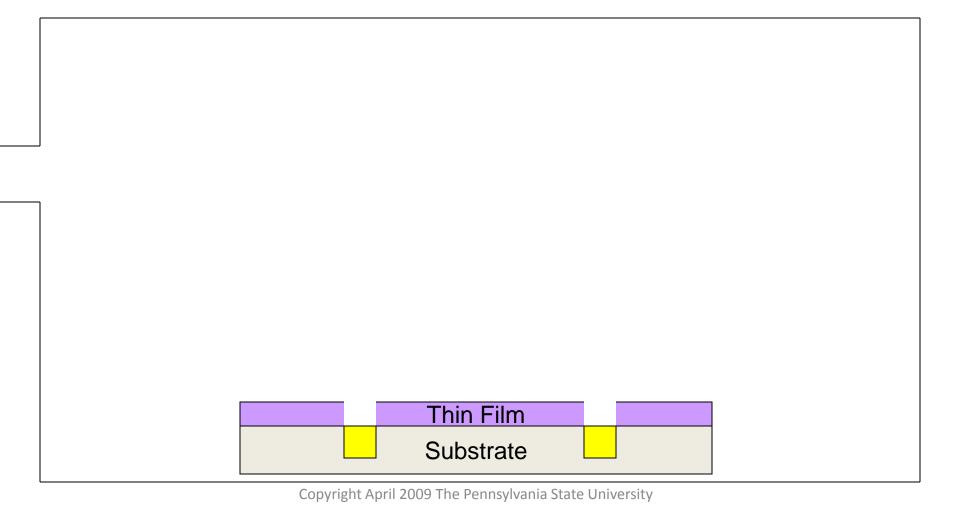
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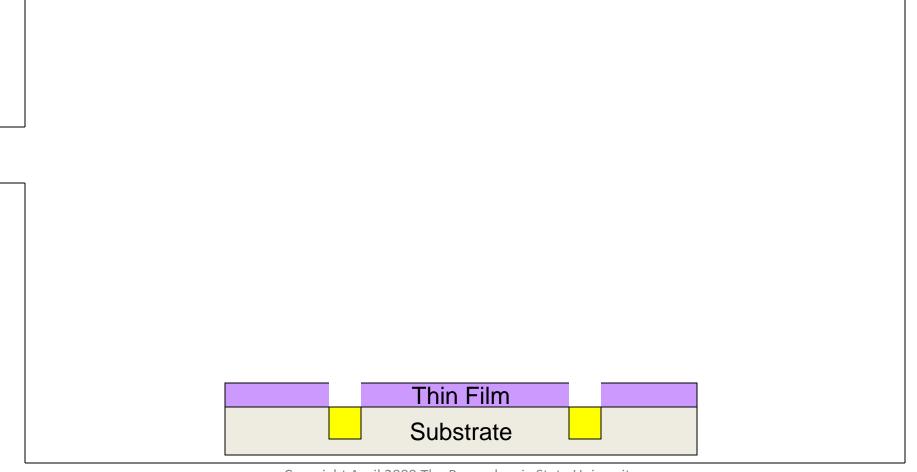
Remove the Photoresist (Etch/Ion Implantation) Barrier

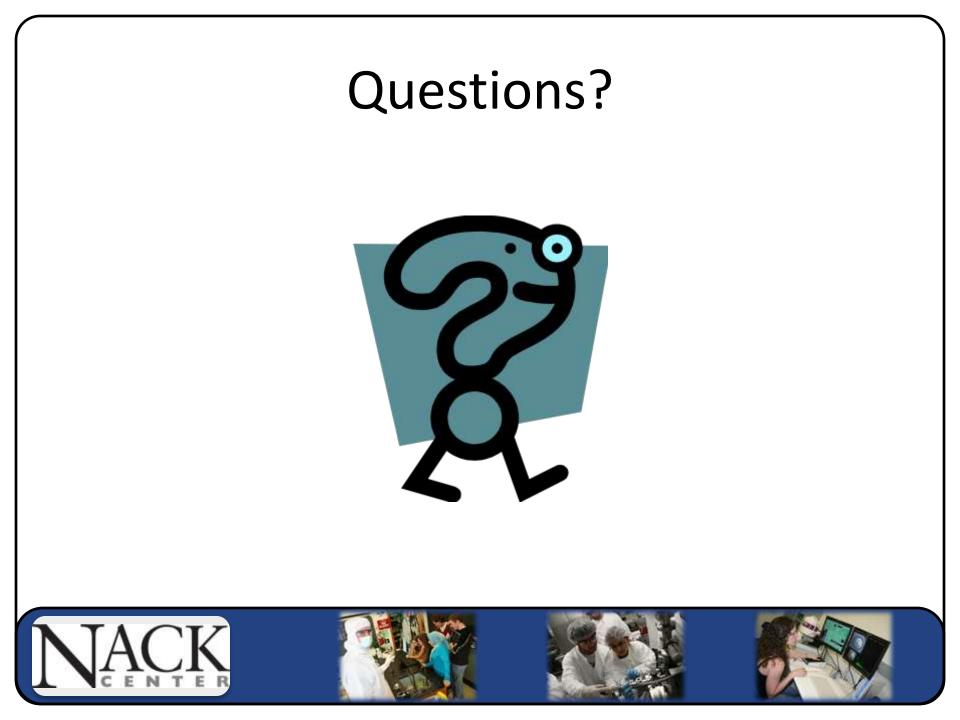


Remove the Photoresist (Etch/Ion Implantation) Barrier



Pattern Transfer and Substrate Modification Complete





# Outline

- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)
  - Deposition (or film growth)
  - Etching ( or removal of material)
- Basic bottom-up approaches in nanofabrication
  - Chemical vapor growth: vapor-solid-liquid growth



# Outline

- Basic top-down approaches in nanofabrication
  - Pattern transfer (lithography)
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- Basic bottom-up approaches in nanofabrication
  - Chemical vapor growth: vapor-solid-liquid growth
  - Self assembly: colloidal chemistry









- Chemical Vapor Growth: Vapor-Liquid-Solid growth (VLS growth)
  - a catalyst is introduced to direct the growth to a specific orientation in a confined area



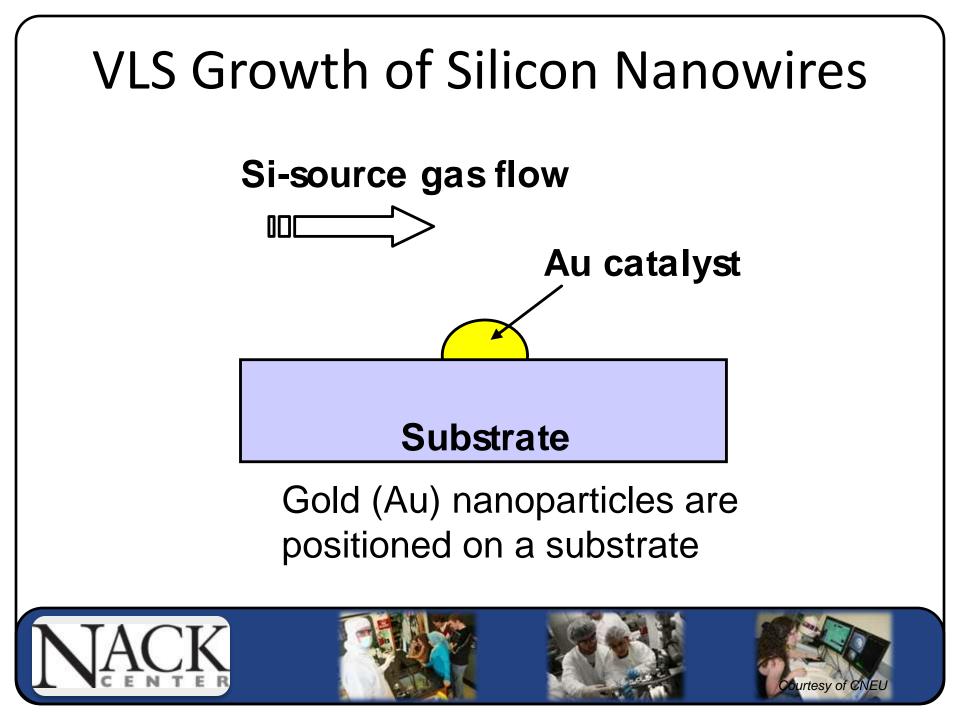
- Chemical Vapor Growth: Vapor-Liquid-Solid growth (VLS growth)
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- Chemical Vapor Growth: Vapor-Liquid-Solid growth (VLS growth)
  - a catalyst is introduced to direct the growth to a specific orientation in a confined area
  - The catalyst forms a liquid droplet that acts as a nucleation site for the growth species
  - Saturation of the catalyst results in precipitation of a sold, resulting in a one dimensional growth



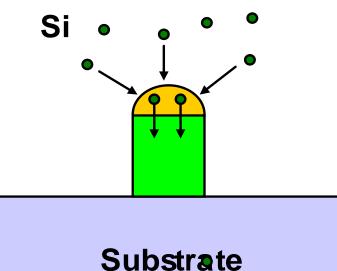




# VLS Growth of Silicon Nanowires Si Substrate Nanoparticles act as a catalyst releasing silicon (Si) from its precursor (source). Si then dissolves into the gold



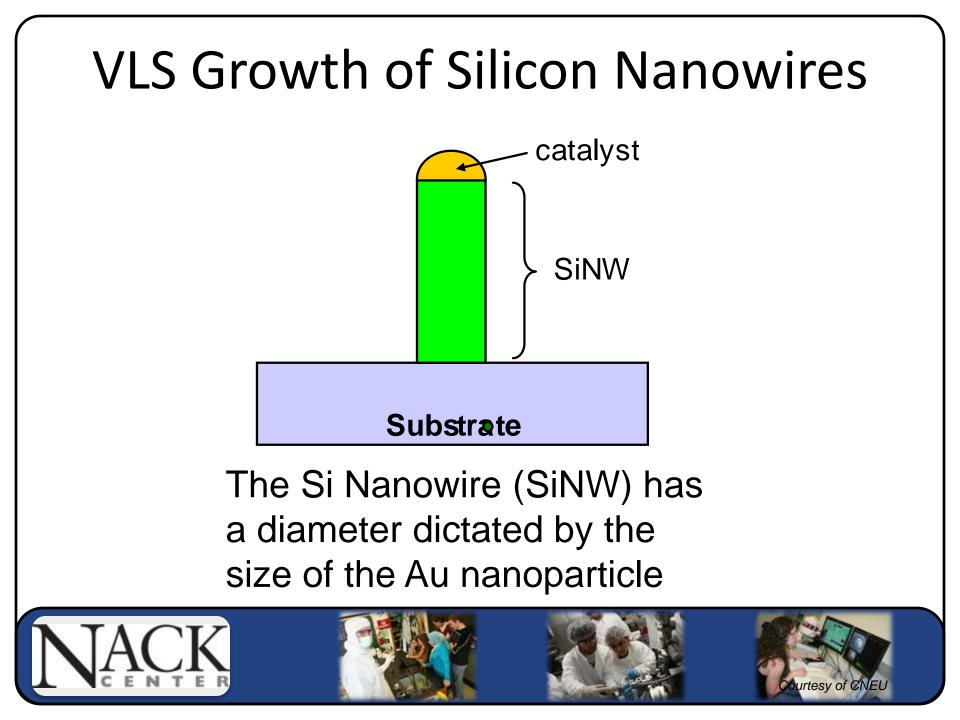
# VLS Growth of Silicon Nanowires

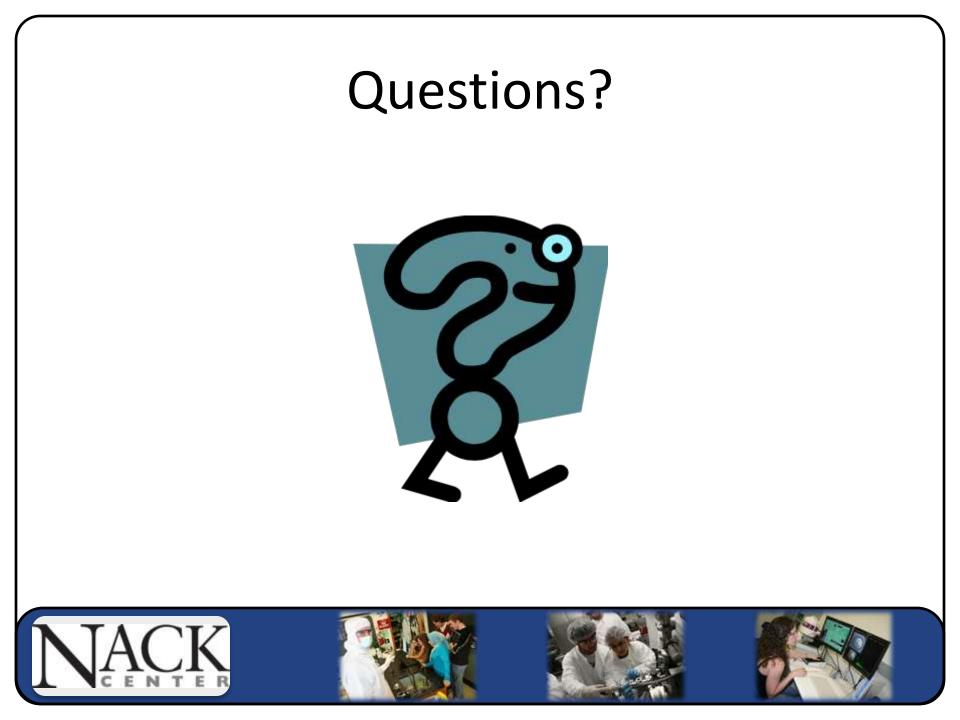


Gold nanoparticle becomes

supersaturated with Si which then precipitates out as a solid nanowire. (shown in green)







- Self assembly: colloidal chemistry
  - Starts with nanoparticles or molecules that aggregate via chemical and physical interactions into the desired nanoscale feature









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  - Starts with nanoparticles or molecules that aggregate via chemical and physical interactions into the desired nanoscale feature
  - The resulting nanostructures may reside in a solution, on a substrate, or in an object



- Self assembly: colloidal chemistry
  - Starts with nanoparticles or molecules that aggregate via chemical and physical interactions into the desired nanoscale feature
  - The resulting nanostructures may reside in a solution, on a substrate, or in an object
  - There is no use of the lithography or etching steps involved.

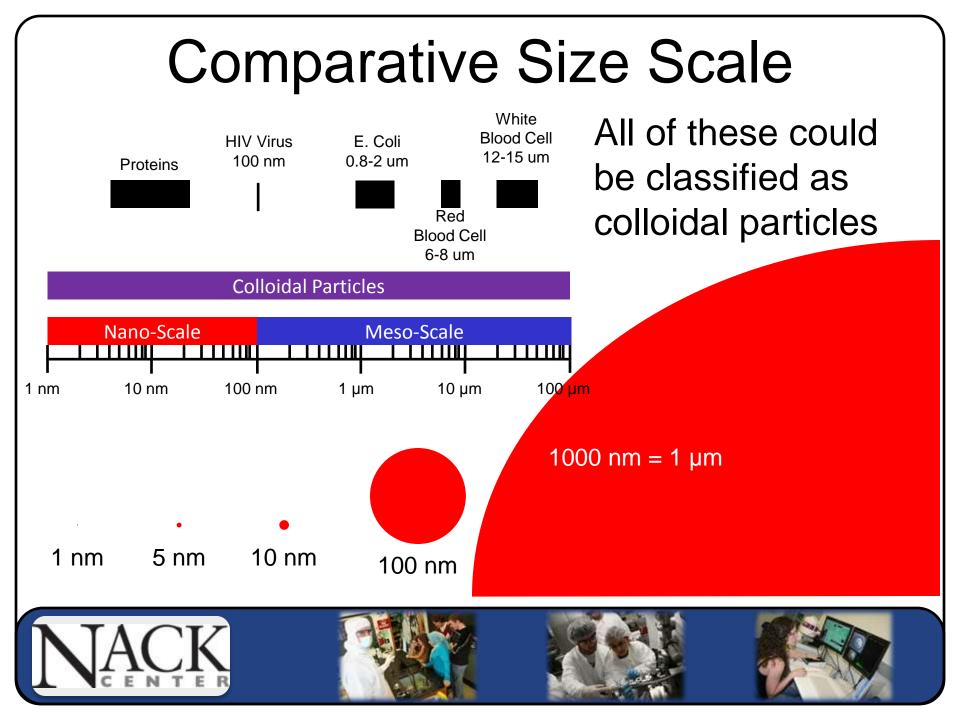


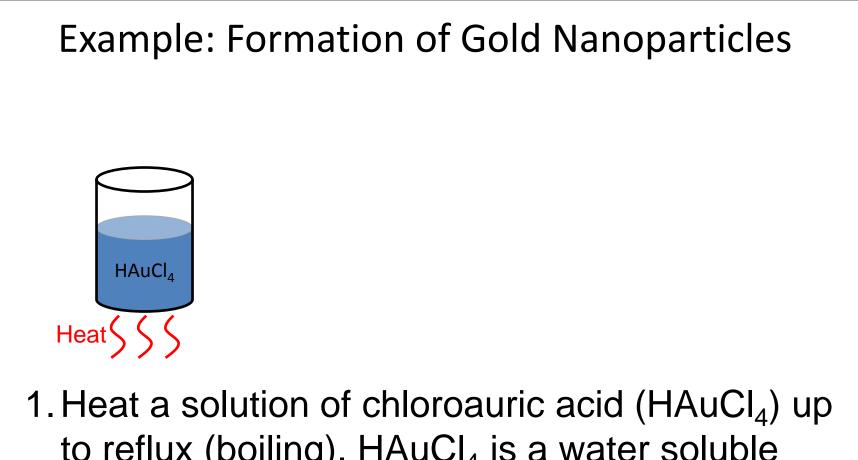
• Colloid: refers to a state of subdivision

- Implies that the molecules or particles dispersed in a medium have at least one dimension roughly between 1 nm and 1  $\mu m.$ 

- Whipped cream
- Milk
- Fog
- Smoke



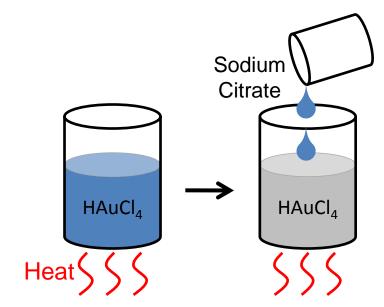




to reflux (boiling). HAuCl<sub>4</sub> is a water soluble gold salt

> http://mrsec.wisc.edu/Edetc/nanolab/gold/index.html J. Chem. Ed. 2004, 81, 544A



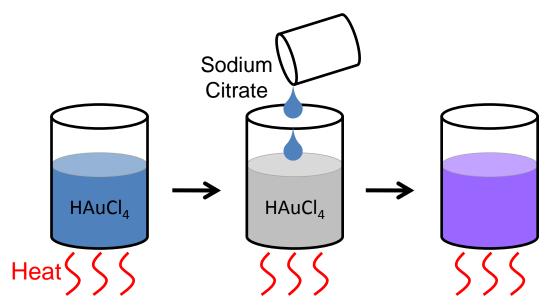


#### 2. Add trisodium citrate, which is a reducing agent

http://mrsec.wisc.edu/Edetc/nanolab/gold/index.html J. Chem. Ed. 2004, 81, 544A.





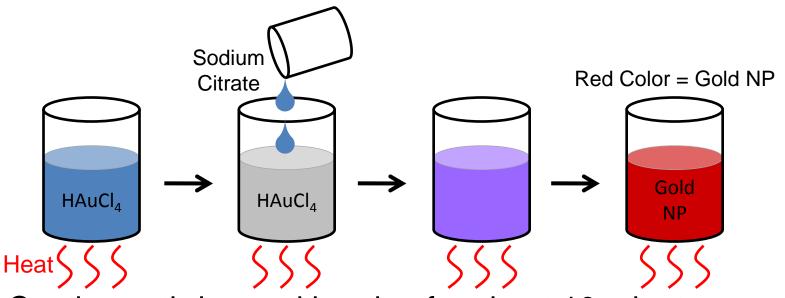


# 3. Continue stirring and heating for about 10 minutes

http://mrsec.wisc.edu/Edetc/nanolab/gold/index.html J. Chem. Ed. 2004, 81, 544A.







3. Continue stirring and heating for about 10 minutes

- During this time, the sodium citrate reduces the gold salt (Au<sup>3+</sup>) to metallic gold (Au<sup>0</sup>)
- The neutral gold atoms aggregate into seed crystals
- The seed crystals continue to grow and eventually form gold nanoparticles http://mrsec.wisc.edu/Edetc/nanolab/gold/index.html J. Chem. Ed. 2004, 81, 544A.

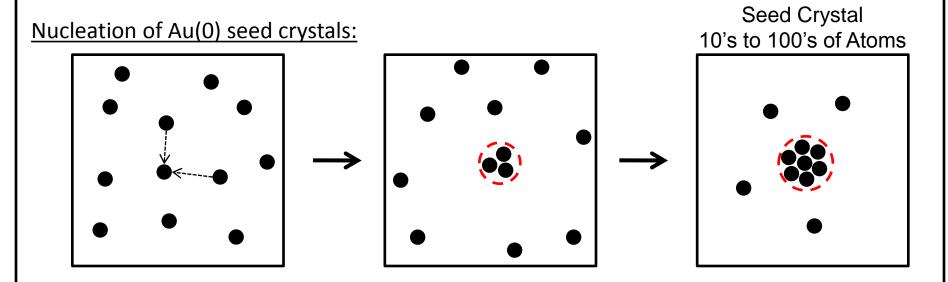








<u>Reduction of gold ions</u>:  $Au(III) + 3e^- \rightarrow Au(0)$ 

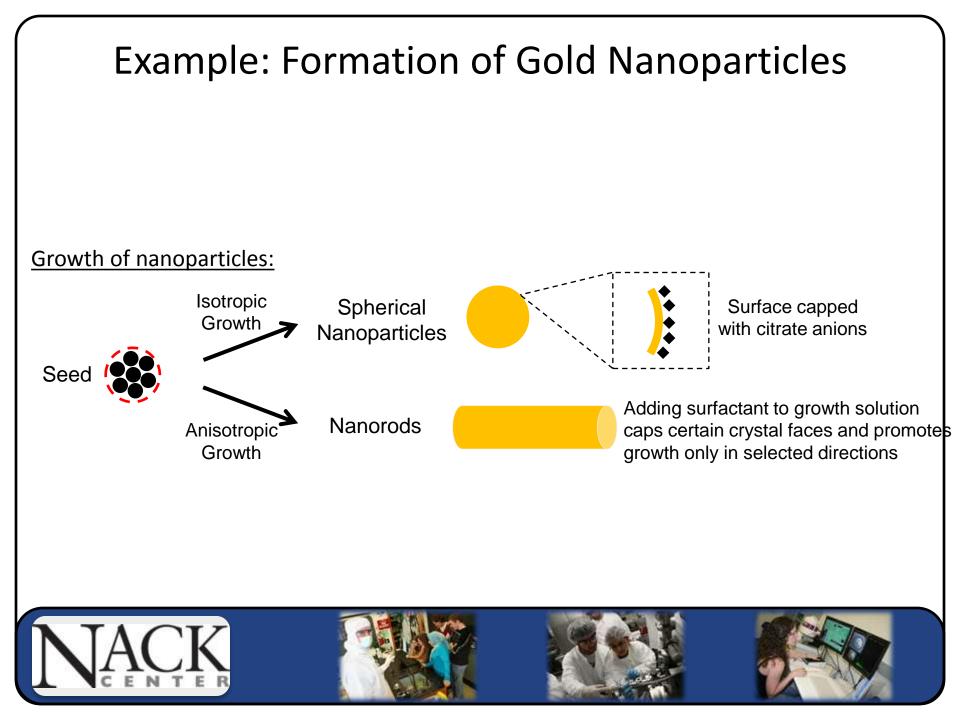


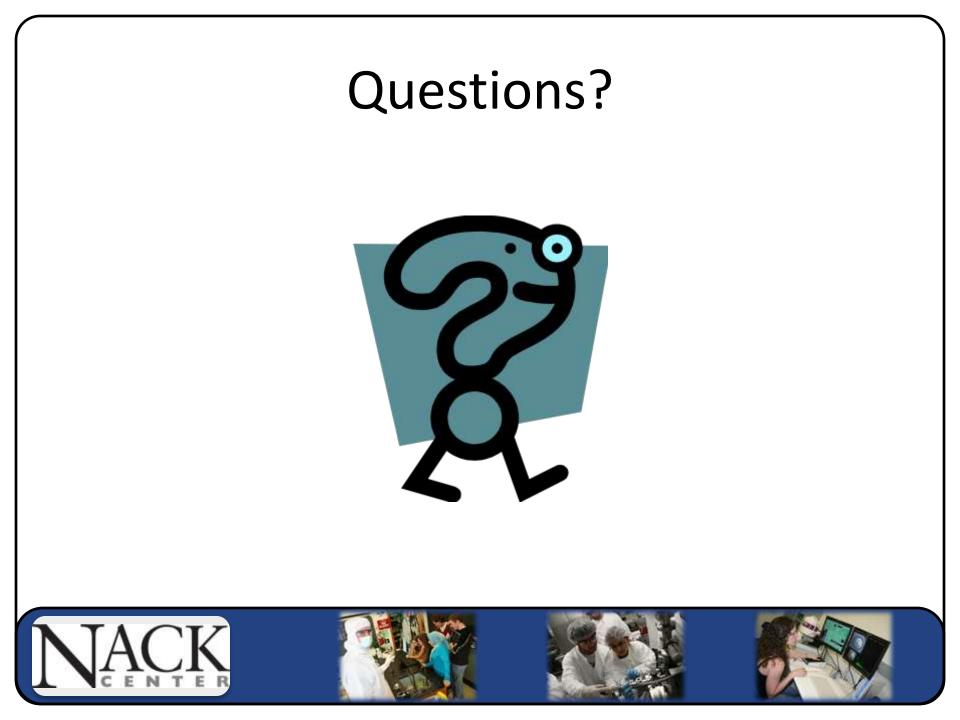












Nano4me.org applications: Introduction of Nanofabrication: Top Down to Bottom Up for the classroom maybe found at: Module 6: How Do You Make Things So Small: An

Introduction to Nanofabrication



Nano4me.org applications: Introduction of Nanofabrication: Top Down to Bottom Up for the classroom maybe found at:

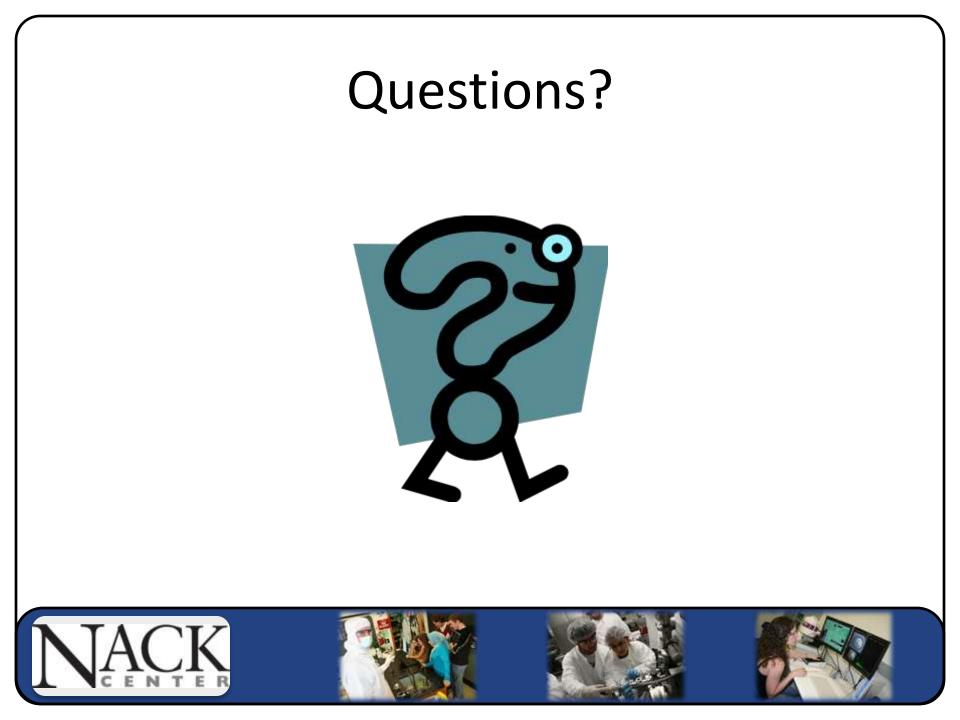
Module 7: How Do You Build Things So Small: Top-Down Nanofabrication



Nano4me.org applications: Introduction of Nanofabrication: Top Down to Bottom Up for the classroom maybe found at:

Module 8: How Do You Build Things So Small: Bottom-Up Nanofabrication





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#### NACK's Webinar

# Introduction to Nanofabrication: Top Down to Bottom Up





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Visit www.highimpact-tec.org as more details develop









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# How Can We Better Serve You?

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http://www.questionpro.com/t/ABkVkZIOXU









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